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ACCEPTED MANUSCRIP<sup>-</sup>

Investigation of barrier inhomogeneities in I-V and C-V characteristics of Ni/n-TiO<sub>2</sub>/p-Si/Al heterostructure

in wide temperature range

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**Abstract** 

In this study, we report on the growth and electrical characterization of Ni/n-TiO<sub>2</sub>/p-Si/Al heterojunction. A thin

layer of TiO<sub>2</sub> was deposited on p-Si by pulsed layer deposition technique. Highly pure nickel and aluminum metals

were deposited by thermal coating system to make the contacts to n-TiO<sub>2</sub> and p-Si, respectively. The pulsed laser

ablation processed Ni/n-TiO<sub>2</sub>/p-Si/Al heterojunction exhibits good rectifying properties over the wide range of

temperature between 80 K to 300 K. The X-ray diffraction (XRD) investigations have confirmed the epitaxial

growth of the TiO<sub>2</sub> films which are highly oriented nanocrystals with particle size of 43.3 nm. The optical energy

band gap of TiO<sub>2</sub> thin films was studied using UV-VIS spectroscopy and Tauc plots, which comes out to be 3.20 eV.

Atomic force microscopy study of the surface morphology reveals that the surface is reasonably smooth, homogeneous and the roughness is of nanometer order. The dominating current transport mechanisms through the

heterojunction were investigated in forward and reverse bias current-voltage (I-V) measurements. The current

transport mechanisms are strong functions of temperature and successfully explained using thermionic emission

diffusion (TED) mechanism with Gaussian distributions of barrier heights. The dependence of barrier height on

temperature and the non-linearity of activation energy plot have confirmed that barrier heights at  $n\text{-TiO}_2/p\text{-Si}$ 

interface follow the Gaussian distributions. The mean value of barrier height and standard deviation were found to

be 0.79 eV and 0.10 V, respectively. The effective resistance of the heterojunction plays an important role in the I-V

characteristics as well as in rectifying properties. The barrier heights as a function of temperature were also studied

from reverse biased capacitance-voltage (C-V) characteristics. The discrepancy between the barrier heights

calculated from I-V and C-V measurements has been attributed to the existence of barrier inhomogeneities and

tunneling factor in the current transport mechanisms. The value of Richardson's constant found to be 1.5×10<sup>5</sup> Am

<sup>2</sup>K<sup>-2</sup> which is of the order of known theoretical value of 3.2×10<sup>5</sup> Am<sup>-2</sup> K<sup>-2</sup>.

Keywords: I-V characteristics, C-V characteristics, Heterojunctions, Gaussian distributions, UV-VIS spectroscopy.

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Introduction

Titanium dioxide (TiO<sub>2</sub>) is a non-toxic n-type wide band gap semiconductor material with low production

cost and high-temperature stability. TiO<sub>2</sub> crystallizes in three polymorphs namely rutile, anatase and brookite.

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